IN THE SPECIFICATION

Please replace paragraph 27 with the following:

[0027] Further, the detector may not substantially limit the solid angle at which the desired radiation emitted by the plasma can be collected through a special optical arrangement (~~an area~~ a solid angle of at least 2π ~~sr~~ steradian (sr) in the case of EUV generation).

Please replace paragraph 28 with the following:

[0028] Following the requirements stated above, the invention adopts the solution of constructing a detection device from a detection module and a projection module with a light waveguide connection therebetween in order to be able to position the optoelectronic detector at a location outside of and at a distance from the interaction chamber which is protected from interfering electromagnetic radiation and particle radiation while nevertheless achieving the necessary closeness of the detection point ~~ad~~ and interaction point by means of a projection module.

Please replace paragraph 52 with the following:

[0052] An enlarged circular section of the target flow 41 is shown at the bottom is Fig. 3. This section shows a view of the surroundings of the detection point 31 in mid-path 43 considered from the direction of the optical axis 32 of the projection module 3. The drawing shows a schematic drop 42, whose diameter (depending on the type and adjustment of the target generator 4) is usually on the order of magnitude between 10 µm and few 100 µm and should be ~~20~~ 10 µm in this specific example, and as an alternative a continuous target flow 41 of the same diameter which is indicated again by dashed lines.